DCC MIP at Penn State, DMR-1539916 Thin Film User Facility - 2021

Ambient-controlled automated growth, wafer transfer and optical characterization of 2D materials

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Multi-module system for metalorganic chemical vapor deposition (MOCVD2) and optical characterization of 2D layered chalcogenide films.





Automated robotic transfer stage moves substrate from growth chamber to glovebox for Raman and photoluminescence spectroscopy without sample exposure to air.



